Amendments to the Claims:

This listing of claims replaces all prior versions and listings of claims in the application:

Listing of Claims:

1-36. (Cancelled)

37. (Previously presented) A method of depositing ink comprising:

delivering ink to an ink chamber; and

applying a jetting voltage across a first electrode and a second electrode on a face of a stiffened piezoelectric element to subject ink within the chamber to a jetting pressure, thereby depositing ink from an exit orifice of the ink chamber, wherein the stiffened piezoelectric element has a region spanning the ink chamber and being substantially completely exposed to the ink chamber, the exposed region having a curved surface over the ink chamber, the curved surface having a substantially constant radius of curvature and being concave relative to the ink chamber.

38. (Previously presented) The method of claim 37, wherein the piezoelectric element includes lead zirconium titanate.

39. (Previously presented) The method of claim 37, wherein the jetting voltage is less than 60 volts.

40. (Previously presented) The method of claim 37, wherein the substantially constant radius of curvature is less than 5 millimeters.

41 – 47 (Cancelled)

48. (New) The method of claim 37, wherein the piezoelectric element has a thickness of 5 to 300 microns.

49. (New) The method of claim 37, wherein the piezoelectric element has a thickness of 10 to 250 microns.

50. (New) The method of claim 37, wherein the piezoelectric element has a thickness of less than 100 microns.

51. (New) The method of claim 37, wherein the chamber has a width of less than 1200 microns.

52. (New) The method of claim 37, wherein the chamber has a width of 50 to 1000 microns.

53. (New) The method of claim 37, wherein the chamber has a width of 100 to 800 microns.

54. (New) The method of claim 37, wherein the curved surface has a radius of curvature of 500 to 3000 microns.

55. (New) The method of claim 37, wherein the curved surface has a radius of curvature of 1000 to 2800 microns.

56. (New) The method of claim 37 , wherein the curved surface has a radius of curvature of 1500 to 2600 microns.

57. (New) The method of claim 37, wherein the electrodes are configured to apply a voltage of less than 60 volts.

58. (New) The method of claim 37, further comprising a series of chambers.

59. (New) The method of claim 59, wherein each of the chambers is covered by a single piezoelectric element.

60. (New) The method of claim 37, wherein the chamber includes a wall contacting the piezoelectric element exposed to the ink chamber at an angle of greater than ninety degrees.